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TRANSMITTAL

Electronic Version v1.1
Stylesheet Version v1.1.0

Title of Invention

METHOD FOR CONTROLLING A PROCESS FOR FABRICATING INTEGRATED DEVICES

Application Number:

10/805136

Date:

2004-03-19

First Named Applicant:

Matthew F Davis

Confirmation Number:

8916

Attorney Docket Number: 8381/ETCH

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Keith P Taboada Registered Number: 45150	/Keith P Taboada/	Attorney
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ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18 Stylesheet Version v18.0

> Title of Invention

METHOD FOR CONTROLLING A PROCESS FOR **FABRICATING INTEGRATED DEVICES**

Application Number:

10/805136

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First Named Applicant: Attorney Docket Number: 8381/ETCH

Matthew Davis

Search string:

(6566025).pn.

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6566025	2003-05-20	McStravick et al.	B1		

Signature

Examiner Name	Date
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Sheet 1 of 1 sheet(s)

PTO Form 1				U.S. Department of Commerce, Patent and Trademark Office				
	(PTO Form 1449 modified)				8381/ETCH/SILICON/JB1		10/805,136	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Applicant Davis, et al.		Confirmation No.: 8916		
(Use soveral shoots if pagessan)			Filing Date		Group			
		Examiner \	DEC 2 3 2004 5		March 19	, 2004		
J.S. Patent	 Docur	ments (Ze TRADE LANGUE		<u></u>			
Examiner nitial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate	
how	A1	4,767,496	08/30/1988	Hieber	156	627		
	A2	5,798,529	08/25/1998	Wagner	250	492.2		
1000	A3	5,926,690	07/20/1999	Toprac et al.	438	17		
1000	A4	5,948,203	09/07/1999	Wang	156	345		
(m)	A5	6,004,706	12/21/1999	Ausschnitt et al.	430	30		
Magal	A6	6,027,842	02/22/2000	Ausschnitt et al.	430	30		
Man	A7	6,161,054	12/12/2000	Rosenthal et al.	700	121		
Marila	A8	6,245,581	06/12/2001	Bonser et al.	438	8		
Min	A9	6,424,417	07/23/2002	Cohen et al.	356	388		
Marila	A10	6,486,492	11/26/2002	Su	257	48		
l Mars	A11	2002/0171828	11/21/2002	Cohen et al.	356	328	07/01/2002	
Foreign Pat	tent De	ocuments						
*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation YES NO	
	B1							
	B2		 					
OTHER AR			<u> </u>	1				
*Examiner		Including Author, Tit	le, Date, Pertine	ent Pages, Etc.				
fin		Lee, et al., "Analysis of Reflectometry and Ellipsometry Data from Patterned Structures," Characterization and Metrology for UCSI Technology: 1998 International Conference, Seiler, et al., eds., pg 331-335						
Min		Raymond, "Angle-resolved scatterometry for semiconductor manufacture,", Microlithography World, Winter 2000.						
pu		Toprac, A., "AMD's Advanced Process Control of Ply-Gate Critical Dimension," Proc. SPIE Vol. 3882, pg 62-65, Sept, 1999.						
pen		Optical Metrology System," Proceedings of SPIE Vol. 4689, March 2002,						
Examiner	L	notroduo	/	not citation is in conf			2/2/05	